IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants	:Sakae KOYATA et al.	Group Art Unit : 1792
Appl. No.	: 10/561,821	Examiner : OLSEN, Allan W.
Filed	: February 7, 2007	Confirmation No. : 2851
For	: PROCESSING METHOD OF SILICON WAFER	

SUBMISSION OF SUPPLEMENTAL DECLARATION

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop **AMENDMENT**
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

Applicants submit herewith an executed Declaration in support of the above-identified application, and supplemental to the executed Declaration filed on February 7, 2007.

Applicants respectfully request that this Supplemental Declaration, which includes corrected foreign priority information and title, be made of record and entered into the prosecution file at the U.S. Patent and Trademark Office.

Authorization is hereby provided to charge and fee required for entry and/or consideration of this paper and the Supplemental Declaration to Deposit Account No. 19-0089.

Should there be any questions, please contact the undersigned at (703) 716-1191.

Respectfully Submitted,
Sakae KOYATA et al.

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September 30, 2009
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Enc. Executed Declaration